Ref #	Hits	Search Query	DBs	Default Operat or	Plura Is	Time Stamp
L1	10	((solder\$3 or bump\$3 or braz\$3) near5 (bond\$3 near5 (stage or station)) near5 (temperature or heat\$3 or reflow\$3 or melt\$3 or cool\$3 or solidification or solidif\$3) near5 (sens\$3 or sensor or control or control\$4))	US-PGP UB; USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 11:39
L2		((solder\$3 or bump\$3 or braz\$3) with (bond\$3 near5 (stage or station)) with (temperature or heat\$3 or reflow\$3 or melt\$3 or cool\$3 or solidification or solidif\$3) with (sens\$3 or sensor or control or control\$4))	US-PGP UB; USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 11:31
L5	4962	(228/1.1,8,9,110.1,180.21, 180.22,49.5,48,49.1,49.2). ccls.	US-PGP UB; USPAT; USOCR	OR	ON	2008/01/22 11:54
L6	7239	(438/108,613,106,612). ccls.	US-PGP UB; USPAT; USOCR	OR	ON	2008/01/22 11:54
L7	629	29/25.01.ccls.	US-PGP UB; USPAT; USOCR	OR	ON	2008/01/22 11:54
L8		5 and ((solder\$3 or bump\$3 or braz\$3) same (bond\$3 near5 (stage or station)) same (temperature or heat\$3 or reflow\$3 or melt\$3 or cool\$3 or solidification or solidif\$3) same(sens\$3 or sensor or control or control\$4))	US-PGP UB; USPAT; USOCR	OR	ON	2008/01/22 11:44

L9	11	6 and ((solder\$3 or bump\$3 or braz\$3) same (bond\$3 near5 (stage or station)) same (temperature or heat\$3 or reflow\$3 or melt\$3 or cool\$3 or solidification or solidif\$3) same(sens\$3 or sensor or control or control\$4))	US-PGP UB; USPAT; USOCR	OR	ON	2008/01/22 11:46
L10	1	7 and ((solder\$3 or bump\$3 or braz\$3) same (bond\$3 near5 (stage or station)) same (temperature or heat\$3 or reflow\$3 or melt\$3 or cool\$3 or solidification or solidif\$3) same(sens\$3 or sensor or control or control\$4))	US-PGP UB; USPAT; USOCR	OR	ON	2008/01/22 11:59
L20	1341	(228/1.1,8,9,110.1,180.21, 180.22,49.5,48,49.1,49.2). ccls.	EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 11:55
L21	2091	(438/108,613,106,612). ccls.	EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 11:54
L22	1645	29/25.01.ccls.	EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 11:54
L23	5060	20 or 21 or 22	EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 11:55

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L28	1	23 and ((solder\$3 or bump\$3 or braz\$3) and (bond\$3 same (stage or station)) and (temperature or heat\$3 or reflow\$3 or melt\$3 or cool\$3 or solidification or solidif\$3) and (sens\$3 or sensor or control or control\$4))	EPO; JPO; DERWEN T; IBM_TDB	OR	ON.	2008/01/22 12:01
L29	12577	5 or 6 or 7	US-PGP UB; USPAT; USOCR	OR	ON	2008/01/22 12:01
L30	75	29 and ((bump same (station or platform or bench or support\$3 or stage or head)) and ((load or wafer or workpiece or component or part or specimen or element) same (transfer\$4 or carrier or transport\$3 or convey\$3 or conveyor or conveyance)) same (control or control\$4 or controllable or controllably or sens\$3 or sensor or regulat\$3 or monitor\$3) same (heat\$3 or temperature or reflow\$3 or cool\$4 or melt\$3 or "pre-heat" or "pre-heating" or (pre near5 heat\$3) or "post-heating" or (post near5 heat\$3) or ((pre or post) with (form\$3 or formation))))	US-PGP UB; USPAT; USOCR	OR	ON	2008/01/22

L31	0	23 and ((bump same	EPO;	OR	ON	2008/01/22
	0	(station or platform or	JPO;			12:50
		bench or support\$3 or	DERWEN			12.50
		• •				
		stage)) and ((load or wafer	T;			
	•	or workpiece or	IBM_TDB			
	•	component or part or				
		specimen or element)				
		same (transfer\$4 or carrier				
		or transport\$3 or	ŧ			
		convey\$3 or conveyor or				
		conveyance or (carry\$3	-			
		near5 (in or out)))) same				
		(control or control\$4 or				
		controllable or controllably				
		or sens\$3 or sensor or				
		regulat\$3 or monitor\$3)				
		same (heat\$3 or				
		temperature or cool\$4 or		•		
		"pre-heat" or "pre-heating"				
		or (pre near5 heat\$3) or				
		"post-heat" or				
	4	"post-heating" or (post				
		near5 heat\$3) or ((pre or				
		post) with (form\$3 or				
		formation))))				

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L32 15	((bump same (station or platform or bench or support\$3 or stage)) and ((load or wafer or workpiece or component or part or specimen or element) same (transfer\$4 or carrier or transport\$3 or convey\$3 or conveyor or conveyance or (carry\$3 near5 (in or out)))) same (control or control\$4 or controllable or controllably or sens\$3 or sensor or regulat\$3 or monitor\$3) same (heat\$3 or temperature or cool\$4 or "pre-heat" or "pre-heating" or (pre near5 heat\$3) or "post-heat" or "post-heat" or "post-heat" or post) with (form\$3 or formation))))	EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22
L33 649	((bump same (station or platform or bench or support\$3 or stage)) and ((load or wafer or workpiece or component or part or specimen or element) same (transfer\$4 or carrier or transport\$3 or convey\$3 or conveyor or conveyance or (carry\$3 near5 (in or out)))) same (control or control\$4 or controllable or controllably or sens\$3 or sensor or regulat\$3 or monitor\$3) same (heat\$3 or temperature or cool\$4 or "pre-heat" or "pre-heating" or (pre near5 heat\$3) or "post-heat" or "post-heat" or "post-heating" or (post near5 heat\$3) or ((pre or post) with (form\$3 or formation))))	US-PGP UB; USPAT; USOCR	OR	ON	2008/01/22

1/22/2008 2:00:23 PM

L34	1	("5878942").PN.	USPAT; USOCR	OR	OFF	2008/01/22 12:57
L35	1	("6787391").PN.	USPAT; USOCR	OR	OFF	2008/01/22 12:57
L36	141	33 and (warp\$3 or buckl\$3 or (thermal near5 deform\$3) or crack\$3 or (pyroelectric near5 effect))	US-PGP UB; USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 13:27
L37	75	((bump near5 (station or platform or bench or support\$3 or stage)) near5 (wafer or silicon or quartz or semiconductor chip) near5 (heat\$3 or temperature or cool\$4 or "pre-heat" or "pre-heating" or (pre near5 heat\$3) or "post-heat" or "post-heating" or (post near5 heat\$3) or ((pre or post) near2 (form\$3 or formation)) near5 (speed or rate)))	US-PGP UB; USPAT; USOCR	OR	ON	2008/01/22 13:31
L38	33	37 and (warp\$3 or buckl\$3 or (thermal near5 deform\$3) or crack\$3 or (pyroelectric near5 effect))	US-PGP UB; USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 13:31

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L39	19	((bump near5 (station or platform or bench or support\$3 or stage)) near5 (wafer or silicon or quartz or semiconductor chip) near5 (heat\$3 or temperature or cool\$4 or "pre-heat" or "pre-heating" or (pre near5 heat\$3) or "post-heating" or (post near5 heat\$3) or ((pre or post) near2 (form\$3 or formation)) near5 (speed or rate)))	EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22
L40		39 and (warp\$3 or buckl\$3 or (thermal near5 deform\$3) or crack\$3 or (pyroelectric near5 effect))	US-PGP UB; USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 13:46
L42	15	(wafer near5 bump\$3 near5 ((pre or post) near5 (heat\$3 or aneal\$3)))	US-PGP UB; USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 13:46
L43	80	(bump\$3 near5 ((pre or post) near5 (heat\$3 or aneal\$3)))	US-PGP UB; USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 13:48

L44	26	43 and (warp\$3 or buckl\$3 or (thermal near5 deform\$3) or crack\$3 or (pyroelectric near5 effect))	US-PGP UB; USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 13:48
L45	1192	((solder\$3 or braz\$3) near5 ((pre or post) near5 (heat\$3 or aneal\$3)))	US-PGP UB; USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 13:48
L46	230	45 and (warp\$3 or buckl\$3 or (thermal near5 deform\$3) or crack\$3 or (pyroelectric near5 effect))	US-PGP UB; USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 13:50
L47	156	46 and ((temperature or cool\$4 or heat\$3) same (control or control\$4 or controllable or sens\$3 or sensor or speed or rate or regulat\$3 or monitor\$3))	US-PGP UB; USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 13:52
L49	106	47 and (station or platform or bench or support\$3 or stage)	US-PGP UB; USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TDB	OR	ON	2008/01/22 13:54